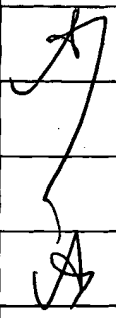
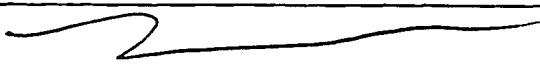



Form PTO 1449 (Modified)		U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE		ATTY DOCKET NO. 242859US0DIV		SERIAL NO. NEW APPLICATION	
LIST OF REFERENCES CITED BY APPLICANT				APPLICANT Hitoshi SAKAMOTO, et al.			
				FILING DATE HEREWITH		GROUP	
U.S. PATENT DOCUMENTS							
EXAMINER INITIAL	DOCUMENT NUMBER	DATE	NAME	CLASS	SUB CLASS	FILING DATE IF APPROPRIATE	
	AA	5,324,690	06/28/94	Gelatos, et al.			
	AB	6,435,130	08/2002	Takaki, et al.			
	AC	6,095,084	08/2000	Shamoulian, et al.			
	AD	4,920,917	05/1990	Nakatani, et al.			
	AE	5,387,288	02/1995	Shatas			
	AF	6,070,551	06/2000	Li, et al.			
	AG	5,891,252	04/1999	Yokogawa, et al.			
	AH	6,015,591	01/2000	Li, et al.			
	AI	5,458,919	10/1995	Okana, et al.			
	AJ						
	AK						
	AL						
	AM						
	AN						
FOREIGN PATENT DOCUMENTS							
	DOCUMENT NUMBER	DATE	COUNTRY	TRANSLATION YES NO			
	AO	2000-133710	05/12/00	Japan			
	AP						
	AQ						
	AR						
	AS						
	AT						
	AU						
	AV						
OTHER REFERENCES (Including Author, Title, Date, Pertinent Pages, etc.)							
	AW	H. Yokoyama, et al., "GROWTH MECHANISM OF CUBIC BORON NITRIDE PREPARED BY PLASMA CVD", Proc. 12th Symp. On Ion Source and Ion Assisted Technology (ISIAT), pgs. 381-386, 1989.					
	AX	M.N.P. Carreno, et al., "LOW TEMPERATURE PLASMA ENHANCED CHEMICAL VAPOUR DEPOSITION BORON NITRIDE", Elsevier Science S. A. 1997 pgs. 008-011					
	AY	T.A. Friedmann, et al., "PULSED LASER DEPOSITION OF BN ONTO SILICON (100) SUBSTRATES AT 600°C", Thin Solid Films, (1994) Vol. 237, pgs. 48-56					
	AZ	M.Z. Karim, et al., "CHARACTERIZATION OF MIXED-PHASE BN THIN FILMS DEPOSITED BY PLASMA CVD", Surface and Coatings Technology (1993) Vol. 60, pgs. 502-505				<input checked="" type="checkbox"/> Additional References sheet(s) attached	
Examiner					Date Considered 7/05		
*Examiner: Initial if reference is considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.							

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				FILING DATE HEREWITH		GROUP	
OTHER REFERENCES (Including Author, Title, Date, Pertinent Pages, etc.)							
	AAA	S.B. Hyder, et al., Journal of the Electrochemical Society, Vol. 123, No. 11, pgs. 1721-1724, "STRUCTURE AND PROPERTIES OF BORON NITRIDE FILMS GROWN BY HIGH TEMPERATURE REACTIVE PLASMA DEPOSITION", November 1976					
	AAB	S.V. Nguyen, et al., Journal of the Electrochemical Society, Vol. 141, No. 6, pgs. 1633-1638, "PLASMA-ASSISTED CHEMICAL VAPOR DEPOSITION AND CHARACTERIZATION OF BORON NITRIDE FILMS", June 1994					
	AAC	A.V. Gelatos, et al., Materials Research Society Symposium Proceedings, Vol. 260, pgs. 347-354, "THE PROPERTIES OF A PLASMA DEPOSITED CANDIDATE INSULATOR FOR FUTURE MULTILEVEL INTERCONNECTS TECHNOLOGY", 1992					
	AAD	T. Sugino, et al., Japanese Journal of Applied Physics, Vol. 39, No. 11A, pgs. 1101-1104, "DIELECTRIC CONSTANT OF BORON NITRIDE FILMS SYNTHESIZED BY PLASMA-ASSISTED CHEMICAL VAPOR DEPOSITION", November 1, 2000					
	AAE						
	AAF						
	AAG						
	AAH						
	AAI						
	AAJ						
	AAK						
	AAL						
	AAM						
	AAN						
	AAO						
	AAP						
	AAQ						
Examiner 				Date Considered 7/05			
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SHEET 1 OF 1

Form PTO 1449 (Modified)		U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE		ATTY DOCKET NO. 242859US0DIV		SERIAL NO. 10/665,473	
LIST OF REFERENCES CITED BY APPLICANT				APPLICANT Hitoshi SAKAMOTO, et al.			
				FILING DATE September 22, 2003		GROUP	
U.S. PATENT DOCUMENTS							
EXAMINER INITIAL		DOCUMENT NUMBER	DATE	NAME	CLASS	SUB CLASS	FILING DATE IF APPROPRIATE
	AA						
	AB						
	AC						
	AD						
	AE						
	AF						
	AG						
	AH						
	AI						
	AJ						
	AK						
	AL						
	AM						
	AN						
FOREIGN PATENT DOCUMENTS							
		DOCUMENT NUMBER	DATE	COUNTRY	TRANSLATION YES NO		
	AO	WO 99/41423	08/19/1999	WIPO			
	AP	7-320538	12/08/1995	JAPAN (with English Abstract)			X
	AQ						
	AR						
	AS						
	AT						
	AU						
	AV						
OTHER REFERENCES (Including Author, Title, Date, Pertinent Pages, etc.)							
	AW						
	AX						
	AY						
	AZ					<input type="checkbox"/> Additional References sheet(s) attached	
Examiner 				Date Considered 7/05			
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